

REMARKS

Reconsideration of the above-referenced application in view of the above amendment, and of the following remarks, is respectfully requested.

Claims 1-7 and 9-10 are pending in this case. Claims 1, 3, and 7 are amended herein and claims 11-12 are cancelled herein.

The Examiner objected to claim 12 as being dependent upon a rejected base claim. Claim 12 is rewritten as amended claim 7 including all the limitations of the base claim (former claim 7), intervening former claim 11, and former claim 12. Accordingly, Applicant respectfully submits that claim 7 and the claims dependent thereon are now allowable.

The Examiner rejected claims 1-5, 7, and 11 under 35 U.S.C. § 103(a) as being unpatentable over Chambers et al. (U.S. Patent 6,518,184).

Applicant respectfully submits that amended claim 1 is patentable over Chambers as there is no disclosure or suggestion in Chambers of forming a silicon nitride layer by transferring the semiconductor body to a chamber, gaseously doping the copper film with silicon by flowing a gas chemistry consisting of silane in the chamber with the RF power off prior to striking a plasma, striking a plasma in the chamber after flowing the silane for at least 0.5 seconds, and then flowing at least one nitrogen-containing source gas into the chamber to deposit a silicon nitride layer over the copper interconnect, as required by claim 1. Accordingly, Applicant respectfully submits that claim 1 and the claims dependent thereon are patentable over Chambers.

Applicant respectfully submits that claim 7 and the claims dependent thereon are patentable over Chambers for the reasons discussed above relative to claim 12.

The Examiner rejected claims 6, 9, and 10 under 35 U.S.C. § 103(a) as being unpatentable over Chambers et al., (U.S. Patent 6,518,184) as applied to claims 1 and 7 above, and further in view of Zistl et al., (U.S. Patent 6,806,191), of record.

Applicant respectfully submits that claims 6, 9, and 10 are patentable over the references for the same reasons discussed above relative to claims 1 and 7 from which these claims depend.

In light of the above, Applicant respectfully requests withdrawal of the Examiner's rejections and allowance of claims 1-7 and 9-10. If the Examiner has any questions or other correspondence regarding this application, Applicant requests that the Examiner contact Applicant's attorney at the below listed telephone number and address.

Respectfully submitted,

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